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LETTERS

Characterization of the cleaning process on a transferred graphene

Li-Wei Huang, Cheng-Kai Chang, Fan-Ching Chien, Kuei-Hsien Chen, Peilin Chen,
Rong Chen and Chia-Seng Chang

J. Vac. Sci. Technol. A 32, 050601 (2014); <http://dx.doi.org/10.1116/1.4886735>

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Surface temperature: A key parameter to control the propanethiol plasma polymer chemistry

Damien Thiry, Francisco J. Aparicio, Priya Laha, Herman Terryn and Rony Snyders
J. Vac. Sci. Technol. A 32, 050602 (2014); <http://dx.doi.org/10.1116/1.4890672>

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Sample-morphology effects on x-ray photoelectron peak intensities. II. Estimation of detection limits for thin-film materials

Cedric J. Powell, Wolfgang S. M. Werner and Werner Smekal

J. Vac. Sci. Technol. A 32, 050603 (2014); <http://dx.doi.org/10.1116/1.4891628>

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Photoluminescence behavior of plasma synthesized Si nanocrystals oxidized at low temperature in pure O₂ and H₂O

Stephen L. Weeks, Rohan P. Chaukulkar, Paul Stradins and Sumit Agarwal

J. Vac. Sci. Technol. A 32, 050604 (2014); <http://dx.doi.org/10.1116/1.4892387>

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Toroidal plasma enhanced CVD of diamond films

John Zvanya, William Holber, Christopher Cullen, Thomas Morris, Andrew Basnett, F Basnett, Jeffrey Hettinger and Robert R. Krchnavek

J. Vac. Sci. Technol. A 32, 050605 (2014); <http://dx.doi.org/10.1116/1.4893416>

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INTERFACES

Effect of interfacial interactions on the thermal conductivity and interfacial therm conductance in tungsten-graphene layered structure

K. Jagannadham

J Vac Sci Technol A 32 051101 (2014); <http://dx.doi.org/10.1116/1.4890576>

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PLASMA SCIENCE AND TECHNOLOGY

Ar ions and oxygen plasma interactions of amine terminated organosilicate glass: combined experimental and *ab initio* simulations study

Haseeb Kazi, Jessica Rimsza, Jincheng Du and Jeffry Kelber

J. Vac. Sci. Technol. A **32**, 051301 (2014); <http://dx.doi.org/10.1116/1.4890119>[+ VIEW DESCRIPTION](#)**Correction of aspect ratio dependent etch disparities**

Robert L. Bates, Matthew J. Goeckner and Lawrence. J. Overzet

J. Vac. Sci. Technol. A **32**, 051302 (2014); <http://dx.doi.org/10.1116/1.4890004>[+ VIEW DESCRIPTION](#)**Smoothing single-crystalline SiC surfaces by reactive ion etching using pure NF₃ NF₃/Ar mixture gas plasmas**

Akimasa Tasaka, Yuki Kotaka, Atsushi Oda, Morihiro Saito, Tetsuro Tojo and Minoru

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SURFACES**Surface oxidation of GaN(0001): Nitrogen plasma-assisted cleaning for ultrahigh vacuum applications**

Subhashis Gangopadhyay, Thomas Schmidt, Carsten Kruse, Stephan Figge, Detlef Hommel and Jens Falta

J. Vac. Sci. Technol. A **32**, 051401 (2014); <http://dx.doi.org/10.1116/1.4886956>[+ VIEW DESCRIPTION](#)**Desorption and sublimation kinetics for fluorinated aluminum nitride surfaces**

Sean W. King, Robert F. Davis and Robert J. Nemanich

J. Vac. Sci. Technol. A **32**, 051402 (2014); <http://dx.doi.org/10.1116/1.4891650>[+ VIEW DESCRIPTION](#)**Evaluating tantalum oxide stoichiometry and oxidation states for optimal memris performance**

Michael T. Brumbach, Patrick R. Mickel, Andrew J. Lohn, Alex J. Mirabal, Michael A. Kalan, James E. Stevens and Matthew J. Marinella

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THIN FILMS**Fabrication of Sr silicate buffer layer on Si(100) substrate by pulsed laser deposit using a SrO target**

Atsuhiro Imanaka, Tsubasa Sasaki, Yasushi Hotta and Shin-ichi Satoh

J. Vac. Sci. Technol. A **32**, 051501 (2014); <http://dx.doi.org/10.1116/1.4886972>[+ VIEW DESCRIPTION](#)

**Mass densification and defect restoration in chemical vapor deposition silicon di
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Kazumasa Kawase, Tsukasa Motoya, Yasushi Uehara, Akinobu Teramoto, Tomoyul
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J. Vac. Sci. Technol. A **32**, 051502 (2014); <http://dx.doi.org/10.1116/1.4886770>

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**Correlation between the structural and cathodoluminescence properties in InGa
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Jing Yang, Degang Zhao, Desheng Jiang, Ping Chen, Jianjun Zhu, Zongshun
Liu, Lingcong Le, Xiaoguang He, Xiaojing Li, Hui Wang, Hui Yang and Uwe Jahn
J. Vac. Sci. Technol. A **32**, 051503 (2014); <http://dx.doi.org/10.1116/1.4889857>

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Effect of AC target power on AlN film quality

Katherine Knisely and Karl Grosh

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**ZnO nanorod growth by plasma-enhanced vapor phase transport with different g
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Chang-Yong Kim, Hee-bong Oh, Hyukhyun Ryu, Jondo Yun and Won-Jae Lee
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**Effect of nitrogen upon structural and magnetic properties of FePt in FePt/AlN mu
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Tenghua Gao, Cong Zhang, Takumi Sannomiya, Shinji Muraishi, Yoshio Nakamura
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Ag-Pd-Cu alloy inserted transparent indium tin oxide electrodes for organic solar

Hyo-Joong Kim, Ki-Won Seo, Han-Ki Kim, Yong-Jin Noh and Seok-In Na

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**Detection of charge carrier confinement into mobile ionic defects in nanoporous
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Juan Borja, Joel L. Plawsky, Toh-Ming Lu, William N. Gill, Thomas M. Shaw, Robert I
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THIN FILMS

Time-dependent dielectric breakdown measurements of porous organosilicate glass using mercury and solid metal probes

Dongfei Pei, Michael T. Nichols, Sean W. King, James S. Clarke, Yoshio Nishi and J. Leon Shohet

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Synthesis of copper nitride films doped with Fe, Co, or Ni by reactive magnetron sputtering

Jianbo Yang, Sajjia Huang, Zhijiao Wang, Yuxuan Hou, Yuyu Shi, Jian Zhang, Jianping Yang and Xing'ao Li

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Hydrogen induced electric conduction in undoped ZnO and Ga-doped ZnO thin films:

Creating native donors via reduction, hydrogen donors, and reactivating extrinsic donors

Housei Akazawa

J. Vac. Sci. Technol. A **32**, 051511 (2014); <http://dx.doi.org/10.1116/1.4892777>

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Superconformal chemical vapor deposition of thin films in deep features

Wenjiao B. Wang, Noel N. Chang, Tracey A. Coddng, Gregory S. Girolami and John R. Abelson

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VACUUM SCIENCE AND TECHNOLOGY

Effect of surface polishing and vacuum firing on electron stimulated desorption from 316LN stainless steel

Oleg B. Malyshev, Benjamin T. Hogan and Mark Pendleton

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Mounting a thermocouple of type E onto a Cu single crystal for use in a magnetically sensitive environment below 77 K

Alexander Potzuweit, Anuschka Schaffner and Heinz Julius Jänsch

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Roll-to-roll atomic layer deposition process for flexible electronics encapsulation applications

Philipp S. Maydannik, Tommi O. Kääriäinen, Kimmo Lahtinen, David C. Cameron, Mikko Söderlund, Pekka Soininen, Petri Johansson, Jurkka Kuusipalo, Lorenza Moro and Xianghui Zeng
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